Abstract

The invention provides an apparatus for stocking and purging a wafer at a ceiling. The apparatus includes: a rail that is formed so as to be installed on a ceiling to guide a vehicle; a stock system that is formed so as to be installed on the ceiling and is formed so as to receive a container, which contains wafers, from the vehicle and stock the container; and a purge assembly that is installed so as to communicate with the container through the stock system and is formed so as to purge the wafers, which are contained in the container, with gas.

Fig. 2